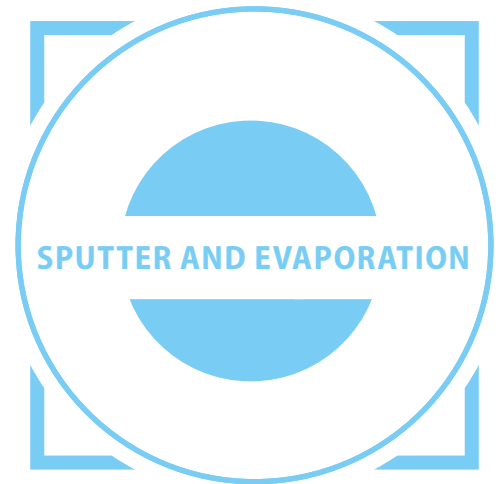


Q150T PLUS

Turbomolecular Pumped Coater



The Q150T Plus is optimised for use with a turbomolecular pump, which gives a lower vacuum down to 5×10^{-5} mbar. This enables the sputtering of oxidising metals, which have a lower grain size suitable for high-resolution imaging. Similarly, lower scattering allows for high purity, amorphous carbon films of high density.

Sputter coating of noble and oxidising metals using the Q150T S & ES Plus:

Recommended for magnifications:

- up to x 50k using Au, Au/Pd
- up to x 100k using Pt
- above x 100k using Cr, Ir

Ideal for thin film applications such as coating with ITO, W, Al, Zn

Other targets are available

Carbon rod coating using the Q150T E and ES Plus.

Recommended applications:

- High-resolution magnification SEM
- Protective platinum layers for FIB
- R&D of corrosion-, friction-, and wear-protective layers
- Protective layers on medical devices
- BSE imaging
- EDX, WDS, EBSD analysis
- Carbon coating of replicas

Q150T Plus features

New user interface has been thoroughly updated:

- **Capacitive touch screen is more sensitive for ease of use**
- **User interface software has been extensively revised, using a modern smartphone-style interface**
- **Comprehensive context-sensitive help screen**
- **USB interface allows easy software updates and backing up/copying of recipe files to USB stick**
- **Process log files can be exported via USB port in .csv format for analysis in Excel or similar. Log**

files include date, time and process parameters.

- **16GB of flash memory can store more than 1000 recipes**
- **Dual-core ARM processor for a fast, responsive display**

Allows multiple users to input and store coating recipes, with a new feature to sort recipes per user according to recent use.

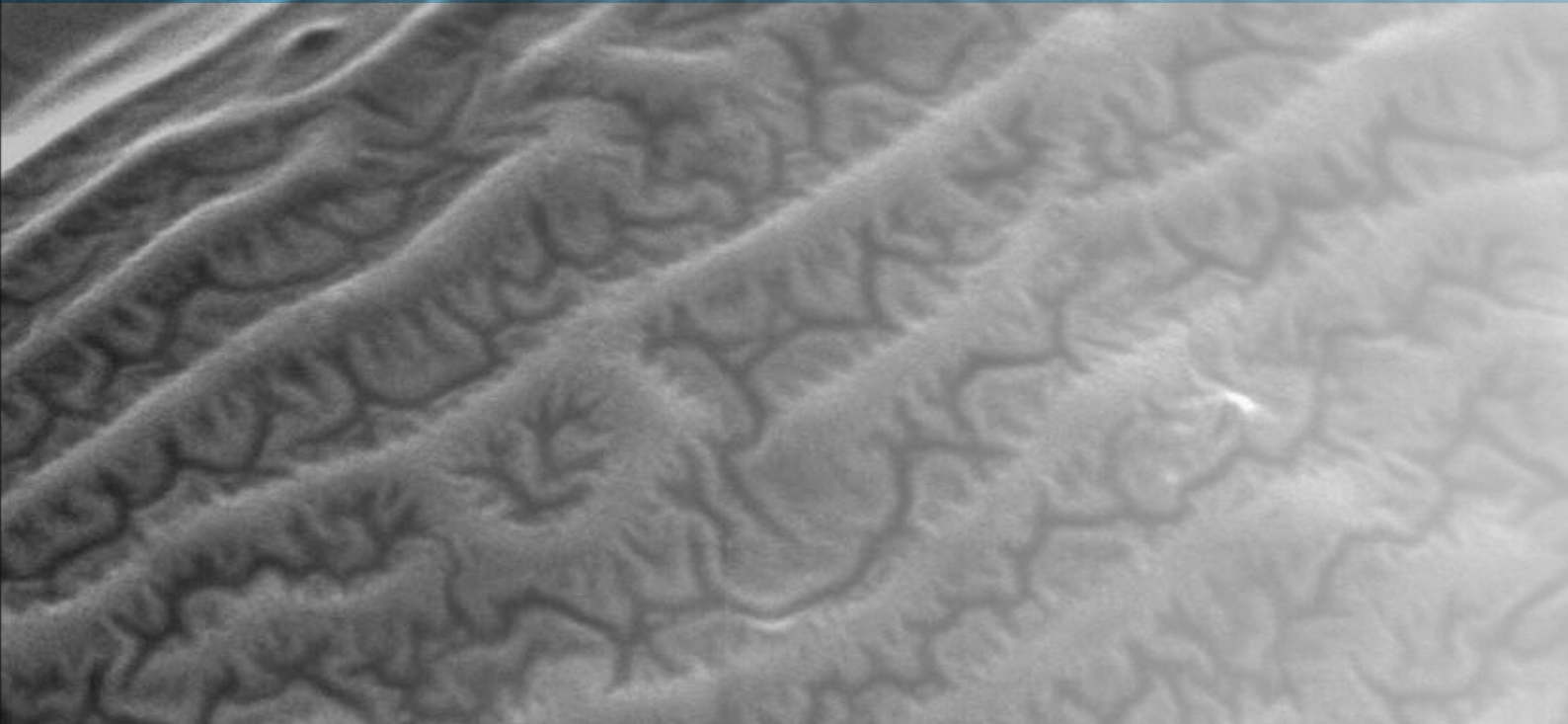
Intelligent system logic automatically detects which insert is in place and displays the appropriate operating settings and controls for that process.

System prompts user to confirm target material and it then automatically selects appropriate parameters for that material.

Intuitive software allows the most inexperienced or occasional operator to rapidly enter and store their own process data. For convenience a number of typical sputtering and carbon coating recipes are already stored but also allows the user to create their own.

Software detects failure to achieve vacuum in a set period of time and shuts down the process in case of vacuum leak, which ensures pump protection from overheating.

Pollen coated in 3nm Au mag x 15k



The Q150T Plus is available in three configurations:

Q150T S Plus

An automatic sputter coater for non-oxidising metals

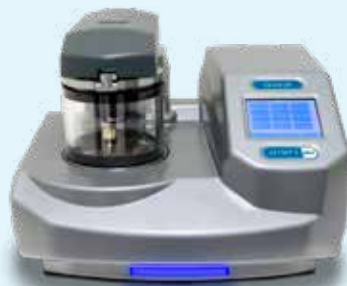
Sputtering targets include Cr, Ir, W, ITO, Al - other targets available



Q150T E Plus

An automatic carbon coater (rod/cord) for SEM applications

Suitable for EDS and WDS. Metal evaporation/aperture cleaning option available.



Q150T ES Plus

A combined system capable of both sputtering and carbon coating

The deposition head inserts can be swapped in seconds. Metal evaporation/aperture cleaning option available.



The Q150T Plus is part of Quorum Technologies internationally acclaimed Q series of coaters, used by thousands of customers worldwide. Designed to provide high-quality coating solutions for SEM, TEM and thin-film applications, the Q series is versatile, affordable and easy to use. **These products are for Research Use Only.**

Automatic, controlled ramped carbon rod evaporation

Careful evaporation allows precise control of carbon thickness (with or without the optional film thickness monitor). The quality of the resulting carbon films is also enhanced by the eradication of "sparking" that is a common feature of less advanced coaters.

For reproducible high-quality carbon films, we would recommend the use of shaped carbon rods. Rods are higher purity, less susceptible to debris and easier to control. Pulsed and ramped carbon rod recipes are supplied as standard.

Cool magnetron sputtering

Sputter coating is a technique widely used in various applications; it is possible to create a plasma and sputter metals with high voltage, poor vacuum and no automation. However, this is not suitable for electron microscopy applications because it will heat the sample and can result in damage when the plasma interacts with the sample. The Q150T Plus series uses low temperature enhanced-plasma magnetrons optimised for the turbomolecular pump pressures, combined with low current and deposition control, which ensures your sample is protected and uniformly coated.

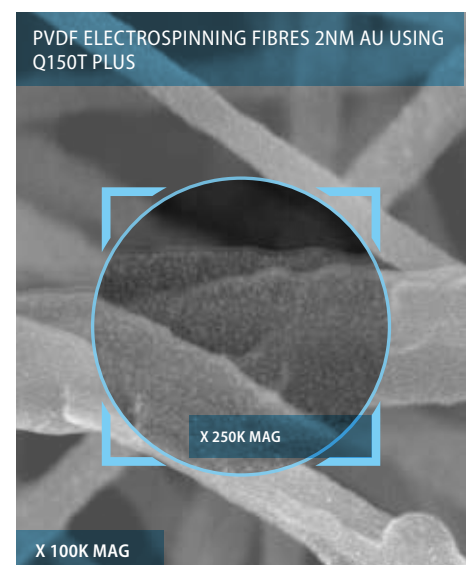
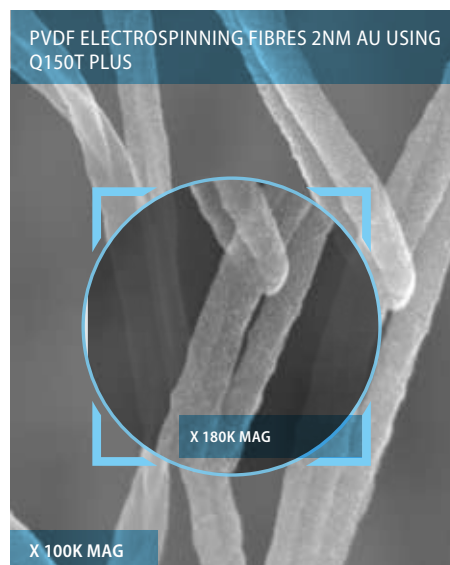
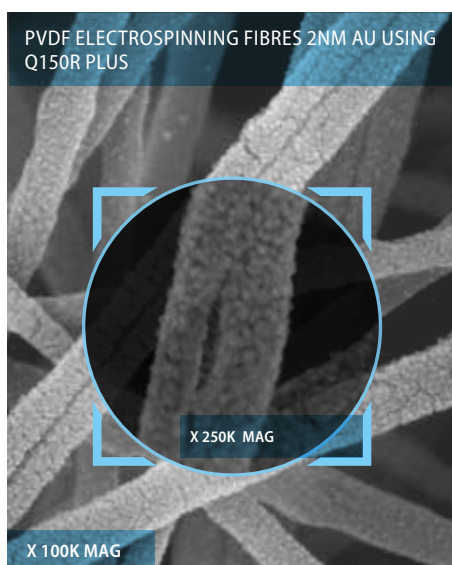
The Q150T S Plus and Q150T ES Plus use easy-change, 57 mm diameter, disc-style targets which are designed to sputter oxidising and noble metals. The Q150T S Plus and Q150T ES Plus are fitted as standard with a chromium (Cr) sputter target. Other targets options include Au, Au/Pd, Pt/Pd, Pd, Pt, Cu, Ir, W, ITO and Al. Others are available on request.

Pulsed cleaning for aluminium sputtering

Aluminium (Al) rapidly forms an oxide layer which can be difficult to remove, but the Q150T ES & S Plus have special recipes for Al that reduce the oxide removal time and prevent excessive pre-sputtering of the target.



Q150T Plus comparative performance:



Dense coating allows for good imaging contrast, although further investigation of a single fibre morphology is difficult. The coating tends to glue together fibres that are close together, making them look like one.

Smaller grain size allows for distinguishing fibre features to be seen and allows for individual fibres to be identified.

Close up on the grain size on the Q150T Plus

Q150T Plus features

Interchangeable plug-in heads

This allows the user to configure the system as a sputter coater, evaporator or glow discharge system - all in one space saving format. A carbon cord evaporation insert is available as an option. Automatic detection of the head type when changed.

Detachable chamber with built-in implosion guard

Removable glass chamber and easily accessible base and top plate allows for an easy cleaning process.

Users can rapidly change the chamber, if necessary, to avoid cross contamination of sensitive samples.

Tall chamber option is available for carbon evaporation to avoid sample heating, improved uniformity for sputtering and to hold taller samples.

Multiple stage options

The Q150T Plus has specimen stages to meet most requirements. All are easy-change, drop-in style (no screws) and are height adjustable (except for the rotary planetary stage).

Some examples:

- **Rotation stage (supplied as standard): 50 mm Ø can accommodate six standard stubs. Height can be pre-set.**
- **Rotate-tilt stage for improved uniform coating: 50 mm Ø. Tilt and height can be pre-set.**
- **Variable angle, rotary planetary stage for heavily contoured samples**
- **Large flat rotation stage with offset gear box for 4"/100 mm wafers**
- **Rotation stage for glass microscope slides**

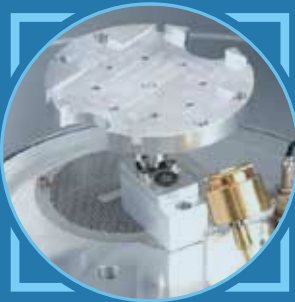
Other options are available on request.

Safety

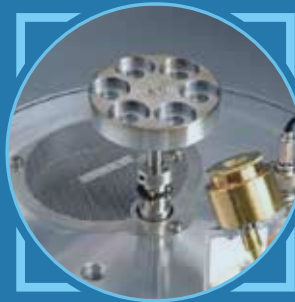
The Q150T Plus meets key industry CE standards

- **All electronic components are protected by covers**
- **Implosion guard prevents user injury in event of chamber failure**
- **Vacuum interlocks remove power from deposition sources to prevent user exposure to high voltage in event of chamber being opened**
- **Electrical interlocks remove power when source head cover opened**
- **Overheating protection shuts down power supply**

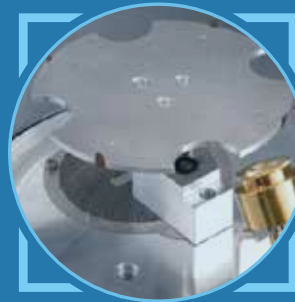
Examples of stages, shown with optional FTM



Microscope slide stage



Rotation stage



Wafer stage



Rotacota planetary stage

Specifications

Instrument case

585 mm W x 521 mm D x 410 mm H (total height with coating head open: 650 mm)

Weight

32 kg (packed: 42 kg)

Packed dimensions

725 mm W x 660 mm D x 680 mm H

Work chamber

Borosilicate glass 150 mm ID x 127 mm H

Display

115.5 mm W x 86.4 mm H (active area), 640 RGB x 480 (display format), capacitive touch colour display

User interface

Full graphical interface with touch screen buttons, includes features such as a log of the last 1000 coatings and reminders for when maintenance is due

Sputter target

Disc-style 57 mm Ø. A 0.3 mm thick chromium (Cr) is fitted as standard. T S and T ES versions only

Specimen stage

50 mm Ø rotation stage with rotation speed of 8-20 rpm. *Other stages available on request.*

Vacuum

Rotary pump: 5 m³/hr two-stage rotary pump with oil mist filter (order separately, see 13034)

Turbo pump: Internally mounted 67 L/sec N₂, air-cooled

Vacuum Measurement: Pirani gauge as standard. A wide range gauge is available as an option

Ultimate vacuum: 5 x 10⁻⁵ mbar*

Sputter vacuum range: Between 5 x 10⁻³ and 1 x 10⁻¹ mbar

**Typical ultimate vacuum of the pumping system in a clean instrument after pre-pumping with dry nitrogen gas*

Processes

Sputtering: Sputter current 1-150 mA to a predetermined thickness (with optional FTM) or by the built-in timer. The maximum sputtering time is 60 minutes (without breaking vacuum and with automatically built-in cooling periods)

Carbon evaporation: Carbon evaporation using rods/cord. Thermal evaporation of metals from filaments or boats. For cleaning TEM apertures a standard molybdenum boat (supplied) can be fitted.

Visual status indicator

A large multi-colour status indicator light provides a visual indication of the state of the equipment, allowing users to easily identify the status of a process at a distance.

The indicator LED shows the following states:

- Initialisation
- Process running
- Idle
- Coating in progress
- Process completed
- Process ended in fault condition

Audio indication also sounds on completion of the process.